

ABSTRACT

5 A substrate processing apparatus includes a reaction
chamber for simultaneously processing a plurality of process
substrates, a boat for loading the process substrates into
the reaction chamber, and a stocker for storing a multiple
number of dummy substrates, at least a portion of the dummy
substrates being loaded into the reaction chamber together
with the process substrates through the use of the boat. A
10 substrate cleaning process is carried out by loading dummy
substrates to be cleaned into the reaction chamber through
the use of the boat and introducing a cleaning gas into the
reaction chamber.

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